

EFFECT OF ATMOSPHERE ON CRYSTALLIZATION OF LiCoO_2 THIN FILM DEPOSITED BY RF SPUTTERING

Cheng-Lung Liao and Kuan-Zong Fung
Department of Materials Science and Engineering
National Cheng Kung University
Tainan 70101, TAIWAN, Republic of China

ABSTRACT

Since 1980s, lithium/lithium-ion batteries have emerged as one of the most important power sources for portable electronics due to their high energy density. In order to reduce weight for portable electronics, the demand for lighter and thinner batteries is increasing. To reduce the battery size, using the thin-film rechargeable battery is the best solution. In thin-film batteries, LiCoO_2 has been widely used as the cathode material due to the advantages of high energy density and good cycleability. The crystalline LiCoO_2 has $R\bar{3}m$ layered structure which provides 2-dimensional accessible path for Li-ion diffusion. Although, the electrochemical properties of thin-film batteries have been investigated recently, the process for the fabrication of thin-film batteries has not been thoroughly studied. Thus, the objective of this work was to study the effect of the atmosphere on the crystallization, morphologies, and electrochemical properties of thin film LiCoO_2 cathode deposited by rf sputtering technique.

In this work, LiCoO_2 thin films with the thickness of about $2\mu\text{m}$ were successfully deposited by rf magnetron sputtering method. The LiCoO_2 target was fabricated by hot-pressing (700°C for 2h in Ar atmosphere) of LiCoO_2 powders which were synthesized from Li_2CO_3 and CoCO_3 at 700°C for 12h. The target was then sputtered in various ratio of Ar and O_2 gas mixture at a total flow rate of 12 sccm under a pressure of 5~50mTorr. The temperature of substrate was kept at $150\sim 350^\circ\text{C}$ during thin film deposition. In order to obtain crystalline LiCoO_2 , the as-deposited films were annealed at $500\sim 700^\circ\text{C}$ for 2h in controlled atmosphere.

The crystallization of LiCoO_2 was characterized by an X-ray diffractometer using $\text{Cu K}\alpha$ radiation. The resistivity of thin films was measured using a DC four-probe method. The morphology of LiCoO_2 thin film was examined by scanning electron microscopy (SEM). The cyclic voltammetry and charge/discharge characteristics of LiCoO_2 were also investigated.

From XRD analysis shown in Fig.1, the as-deposited film exhibits an amorphous structure. After annealing at 500°C for 2h, the amorphous phase started to crystallize. As the annealing temperature increased, the crystallization was also enhanced. Under the flow of pure Ar during deposition, the annealed and crystallized LiCoO_2 films exhibited (104) preferred orientation. However, under the flow of 75% O_2 and 25% Ar, the intensity of (101) reflection from annealed LiCoO_2 film become stronger than that of (104) reflection as shown in Fig.2. As the annealing temperature increased to 700°C , the reflections representing Co_3O_4 were also observed. During deposition and crystallization process, the rearrangement of Li, Co and O ions is strongly dependent upon the content of oxygen. Under oxygen-rich atmosphere, it is believed that LiCoO_2 crystallized preferably along oxygen-rich planes. Therefore, (101) reflection became stronger than (104) reflection. After the annealing and crystallization process, finely distributed columnar LiCoO_2 crystallites were observed as shown in Fig.3.

Acknowledgment : This work is supported by NHRI, Taiwan under the contract #NHRI-GT-EX89E924L

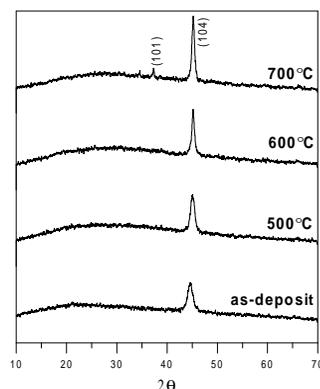


Fig.1 XRD patterns of LiCoO_2 thin films (deposited in $\text{Ar}=12\text{sccm}$) annealed at various temperatures for 2h

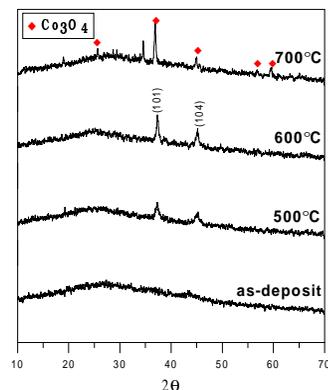


Fig.2 XRD patterns of LiCoO_2 thin films (deposited in $\text{Ar}=3\text{sccm}$ and $\text{O}_2=9\text{sccm}$) annealed at various temperatures for 2h

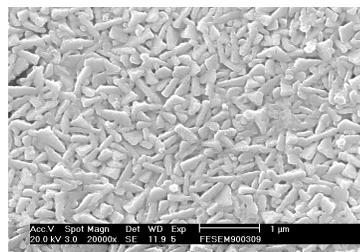


Fig.3 SEM morphology of LiCoO_2 thin film (deposited in $\text{Ar}=12\text{sccm}$) annealed at 700°C for 2h